## Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

## Listing of claims:

Claim 1 (currently amended): A MOS transistor in a singletransistor memory cell, comprising:

a semiconductor substrate having a substrate surface, a first conductive region and a second conductive region;

a gate oxide disposed on said substrate surface;

a gate disposed on said gate oxide over an area between said first conductive region and said second conductive region and having side walls adjacent respective ones of said conductive regions, said gate including a tungsten silicide layer and a polysilicon layer;

a silicon oxide passivation layer disposed on said side walls of said gate; and

an insulating silicon nitride spacer disposed on said silicon oxide passivation layer, said spacer acting as an oxidation barrier;

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said gate oxide insulating said gate from said semiconductor substrate and having a thickened area in a region below at least one of said side walls adjacent said conductive regions.

Claim 2 (cancelled).

Claim 3 (previously presented): The MOS transistor according to claim 1, wherein said gate includes a layer selected from the group consisting of a tungsten silicide layer and a polysilicon layer.

Claims 4-6 (cancelled).

Claim 7 (currently amended): A selection transistor in a DRAM memory cell, comprising the MOS transistor according to claim  $4\ \underline{1}$ .

Claim 8 (original): A selection transistor in a DRAM memory cell, comprising the MOS transistor according to claim 1.